

Kaushik Varma Sagi

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/10193236/publications.pdf>

Version: 2024-02-01

8
papers

198
citations

1307366
7
h-index

1719901
7
g-index

8
all docs

8
docs citations

8
times ranked

95
citing authors

| # | ARTICLE | IF | CITATIONS |
|---|--|-----|-----------|
| 1 | Citric Acid as a Complexing Agent in Chemical Mechanical Polishing Slurries for Cobalt Films for Interconnect Applications. ECS Journal of Solid State Science and Technology, 2017, 6, P594-P602. | 0.9 | 59 |
| 2 | Role of Guanidine Carbonate and Crystal Orientation on Chemical Mechanical Polishing of Ruthenium Films. ECS Journal of Solid State Science and Technology, 2013, 2, P445-P451. | 0.9 | 41 |
| 3 | Chemical Mechanical Polishing of Chemical Vapor Deposited Co Films with Minimal Corrosion in the Cu/Co/Mn/SiCOH Patterned Structures. ECS Journal of Solid State Science and Technology, 2017, 6, P276-P283. | 0.9 | 40 |
| 4 | Potassium Permanganate-Based Slurry to Reduce the Galvanic Corrosion of the Cu/Ru/TiN Barrier Liner Stack during CMP in the BEOL Interconnects. ECS Journal of Solid State Science and Technology, 2016, 5, P256-P263. | 0.9 | 18 |
| 5 | Investigation of Guanidine Carbonate-Based Slurries for Chemical Mechanical Polishing of Ru/TiN Barrier Films with Minimal Corrosion. ECS Journal of Solid State Science and Technology, 2014, 3, P227-P234. | 0.9 | 14 |
| 6 | Role of Ce ³⁺ ions in Achieving High Silicon Nitride Polish Rates. ECS Journal of Solid State Science and Technology, 2017, 6, P898-P903. | 0.9 | 14 |
| 7 | Chemical Mechanical Polishing and Planarization of Mn-Based Barrier/Ru Liner Films in Cu Interconnects for Advanced Metallization Nodes. ECS Journal of Solid State Science and Technology, 2017, 6, P259-P264. | 0.9 | 12 |
| 8 | Mitigation of corrosion challenges for barrier films at advanced nodes. , 2016, , . | | 0 |